



Optica Applicata 2009(Vol.39), No.3, pp. 459-465

The study of the good polishing method for polymer SU-8 waveguide

Mohammad Syuhaimi Ab-Rahman, Fazlinda Ab-Aziz, Noor Azie Azura Mohd Arif, Saiful Dzulkefly Zan, Seri Mastura Mustaza, Abang Anuar Ehsan, Sahbudin Shaari

SEARCH

[Advanced search](#)

Keywords

waveguides polishing, SU-8 polymer, rotational speed, sandpaper, silicon, cut off length

Abstract

This research focused on polish characteristic of polymer based waveguides. The aim of the research was to show how polishing parameters affect the cut length of the end surface of SU-8 polymer on silicon and to determine the best parameters for polishing SU-8 polymer. Then, four samples were used for characterizing the polishing of polymer. Each sample was polished with the same rotation and sandpaper size but with different rotational speed. The experiment result shows that the best rotational speed for polishing polymer SU-8 sample on silicon is 200 rpm.



842.1 kB

[Back to list](#)

© Copyright 2007 T.Przerwa-Tetmajer All Rights Reserved 2007

[About Optica Applicata](#)

[Current issue](#)

[Browse archives](#)

[Search](#)

[Editorial Board](#)

[Instructions for Authors](#)

[Ordering](#)

[Contact us](#)